

# MOORE & More than MOORE









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### **MEMS/NEMS INFRASTRUCTURE** in CER MICROSYSTEMS LAB



#### **Micromachining techniques:**

- Patterning mask design, laser pattern generator, 1µm photolithography, (double side) alignment, electron beam lithography (E-Beam), Focused Ion Beam processing – FIB milling, nanoimprinting
- Structured polymer layers PMMA, PI, SU8 patterning, micromoulding, soft lithography PDMS
- Wet chemistry chemical wafer cleaning, isotropic and anisotropic etching techniques
- Dry etching deep reactive ion etching, plasma etching techniques (DRIE, RIE)
- High temperature processes thermal oxidation, diffusion, annealing, rapid thermal annealing (RTA)
- Physical thin film depositions Thermal and electron beam evaporation, DC and RF Sputtering
- Chemical thin film depositions Atmospheric and Low Pressure Chemical Vapour Deposition (CVD, LPCVD, LTO) thermal and plasma enhanced Atomic Layer Deposition (ALD)
- Liquid Phase Epitaxy (LPE) of III-V compound semiconductors (LED manufacturing)
- Wafer bonding Si-glass, glass-glass, polymer-glass anodic and thermal bonding
- Chip dicing, wire bonding especially for sensor applications
- Special packaging techniques and methods
- multi-domain Finite-Element Modelling (FEM), and process simulation.

#### Zeiss-SMT LEO 1540 XB SEM/FIB SCIOS-2 type dual-beam SEM/FIB nanoprocessing systems

SEM with focused ion beam (FIB),

RAITH 150 E-BEAM

gas injection system (GIS for EBAD/IBAD)

#### **Characterisation techniques:**

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 optical (fluorescent) and electron microscopy (SEM / TEM and EDS), atomic force microscopy (AFM), profilometry, electrochemical impedance spectroscopy (EIS), mechanical vibration and climate test chambers, UV / VIS / IR / FTIR spectroscopy, etc.





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# **SILICON** (silex)



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# SILICON (silex)

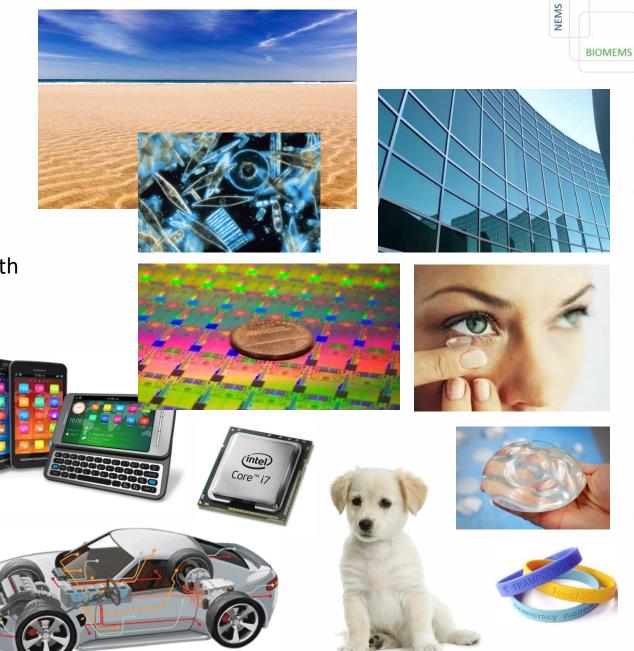
Discoverer: Jons Berzelius 1823, Sweden

#### Natural presence: granite, quartz, clay, sand

2nd in incidence in the Earth

Other applications...



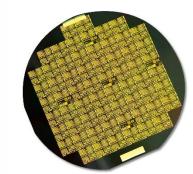


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#### SILICON – chemical element







**Properties:** gray, metallic, extremely hard material

Atomic number: 14 (1s2 2s2 2p6 / 3s2 3p2)

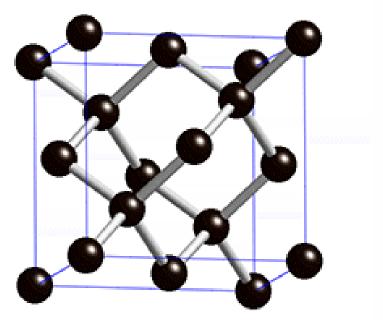
4th group / tetravalent metalloid

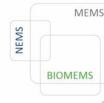
Crystal: similar to diamond

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**Electronic property:** <u>semiconductor</u>





NEMS BIOMEMS Freeze Out Resistance of semiconductors:  $10^{-9} - 10^3 1/\Omega cm$ ρ How does the resistance change with the temparature? negative thermal coefficient Energy of electrons of resistance Intrinsic Conduction Band Extrinsic Large energy gap between Fermi valence and Conduction Band level conduction bands. Т Conduction Band ELKH | Centre for Energy Research | Institute of Technical Physics and Material Valence Band Valence Band Valence Band 3×10<sup>15</sup> Si a. Insulator b. Semiconductor c. Conductor Electron Density (cm<sup>.3</sup>)  $(cm^{.3})$  $N_{D} = 10^{15} cm^{-3}$ Intrinsic region Phosphorus Gallium Conduction band Conduction band Conduction band New band Extrinsic region qap Donor level Band Acceptor level qap New band **•** e gap Freeze-out Valence band Add Valence band Add Valence band region P-doped silicon Ga-doped silicon n, aroup 13 group 15 atoms atoms Pure silicon *n*-Type semiconductor p-Type semiconductor 0 (a) Doping with a group 15 element (b) Doping with a group 13 element 100 200 300 400 500 600 0 T (K)

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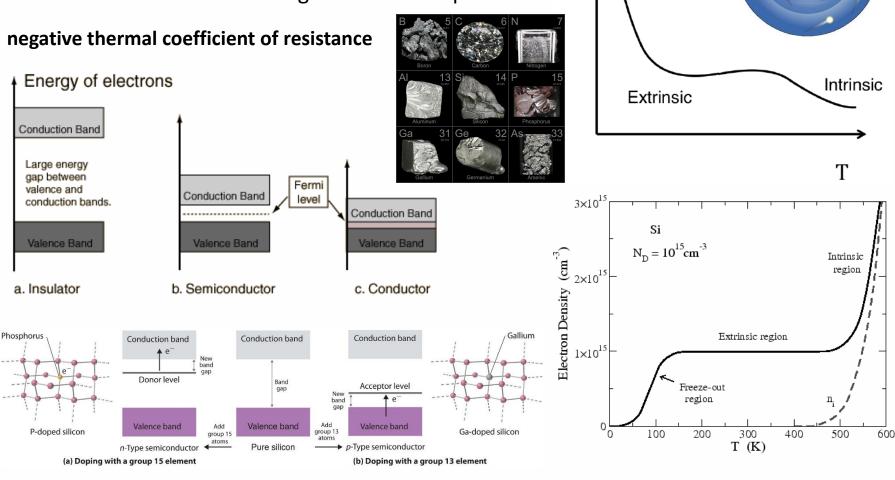
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#### SEMICONDUCTORS

Resistance of semiconductors:  $10^{-9} - 10^3 1/\Omega cm$ 

How does the resistance change with the temparature?



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Freeze Out

ρ

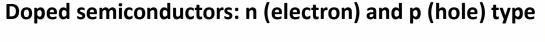
#### DIODE

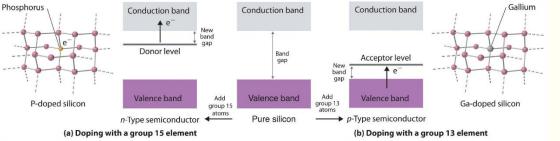
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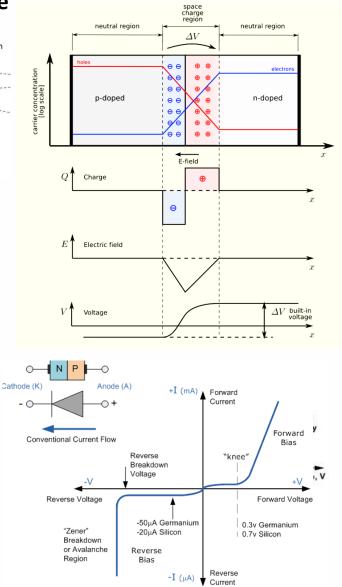
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#### TRANSISTOR





# **The Nobel Prize in Physics** 1956



William Bradford Shockley Prize share: 1/3



John Bardeen Prize share: 1/3



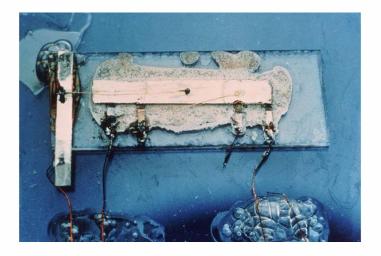
Walter Houser Brattain Prize share: 1/3

The Nobel Prize in Physics 1956 was awarded jointly to William Bradford Shockley, John Bardeen and Walter Houser Brattain "for their researches on semiconductors and their discovery of the transistor effect".

Substitution of vacuum (electron) tube Functions: switching / amplication / voltage stabilisation



#### THE FIRST INTEGRATED CIRCUIT

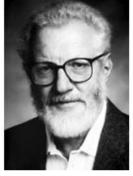


- Transistor: solution for the problems of the vacuum (electron) tube (dissipation, relability).
- Solution for connecting discrete devices (space saving).

#### **The Nobel Prize in Physics** 2000



Zhores I. Alferov Prize share: 1/4



Herbert Kroemer Prize share: 1/4

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Jack S. Kilby Prize share: 1/2

The Nobel Prize in Physics 2000 was awarded "for basic work on information and communication technology" with one half jointly to Zhores I. Alferov and Herbert Kroemer "for developing semiconductor heterostructures used in high-speed- and optoelectronics" and the other half to Jack S. Kilby "for his part in the invention of the integrated circuit".

Photos: Copyright © The Nobel Foundation



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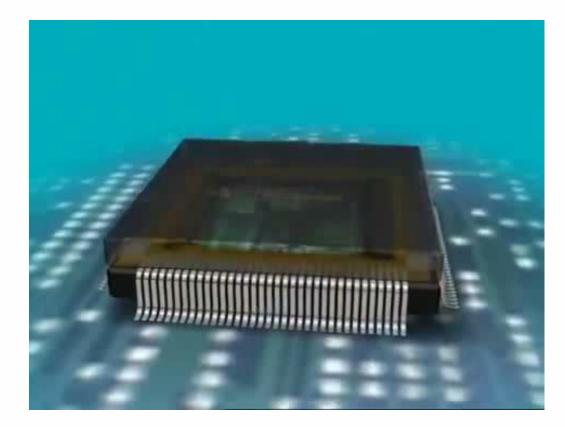
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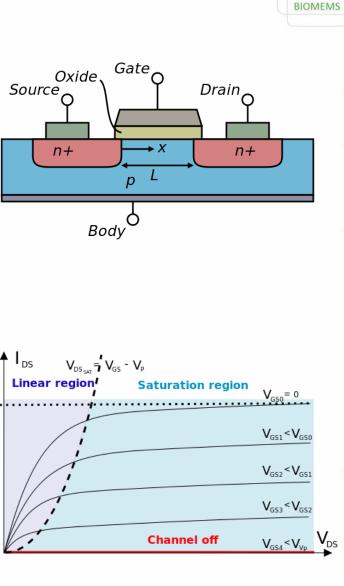
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# FIELD EFFECT TRANSISTOR (FET)

#### Main building block of CPU and memory

Functions: amplification (analog signals), switching





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#### COMPUTATION

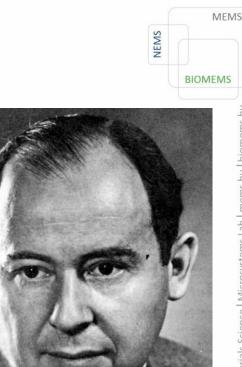




### The FIRST COMPUTER

#### Von Neumann, János (1903-1957)

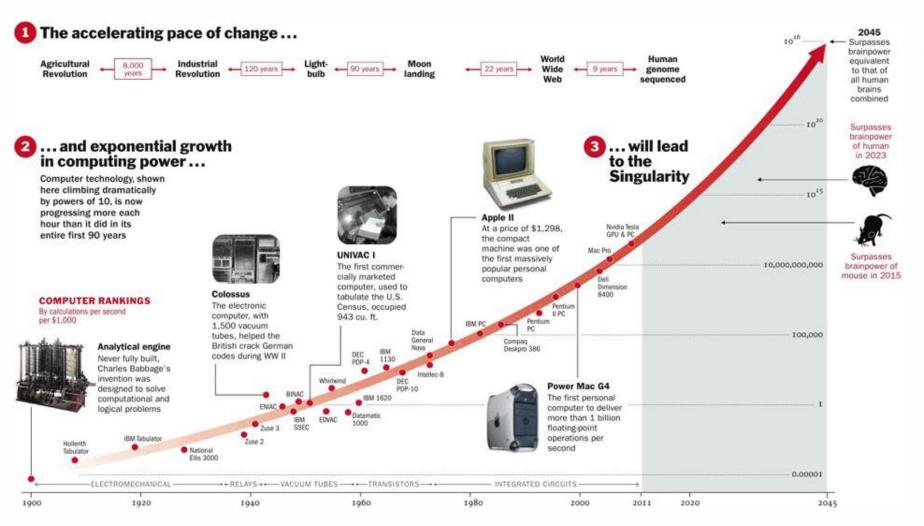




Development of the logical architecture of the electronic computers, based on the binary system.

Basic elements: memory, program storage, command system

### **DEVELOPMENT of THE COMPUTATIONAL CAPACTY**

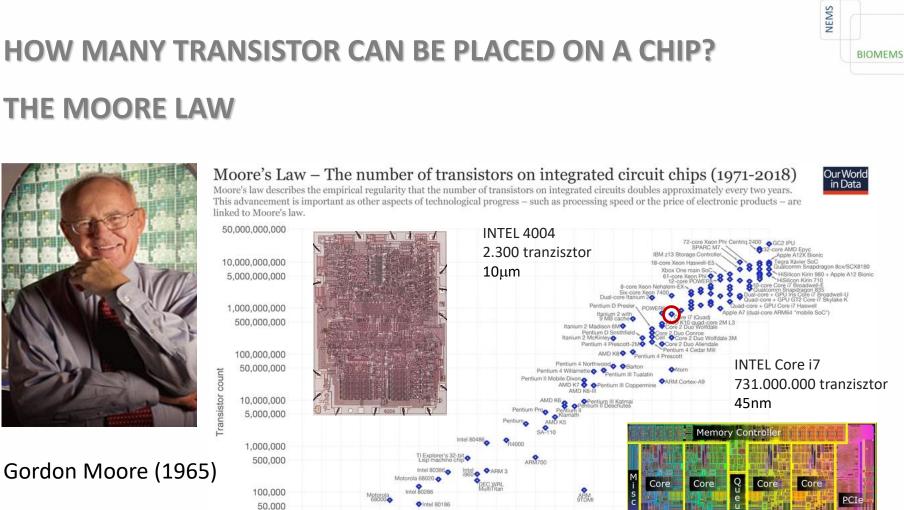


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1,000

OARM 2

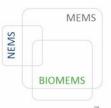
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Shared L3 Cache

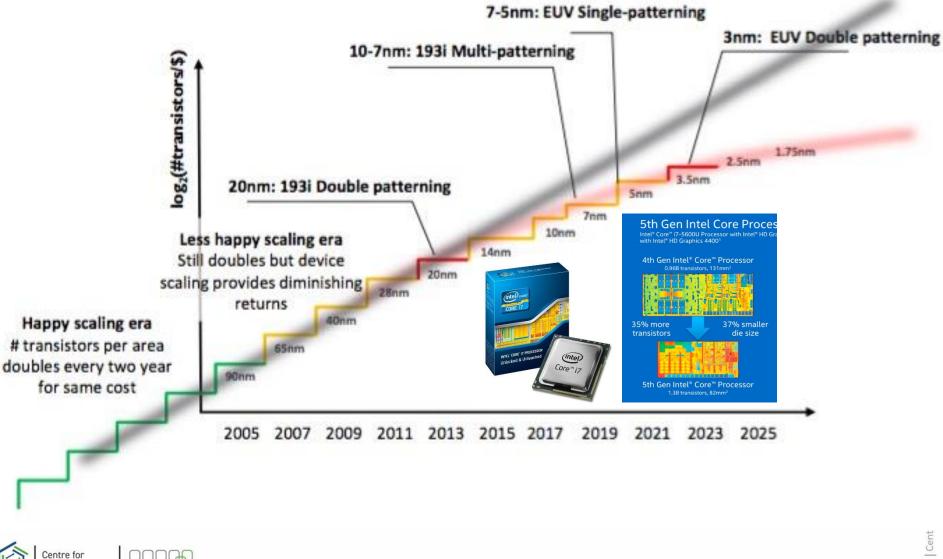
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#### **TECHNOLOGY DEVELOPMENT**



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#### **TECHNOLOGY: from SAND to PROCESSOR**

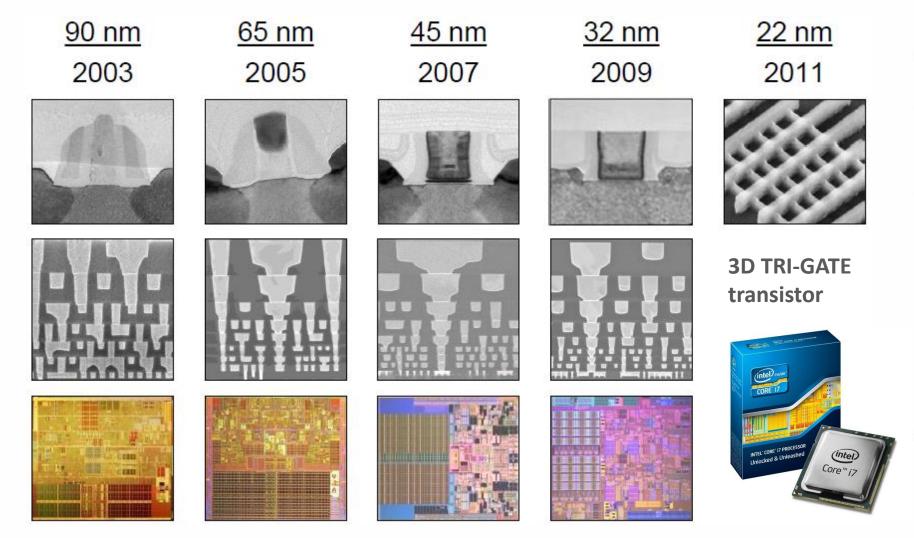




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#### **INTEL 2003 - 2011**



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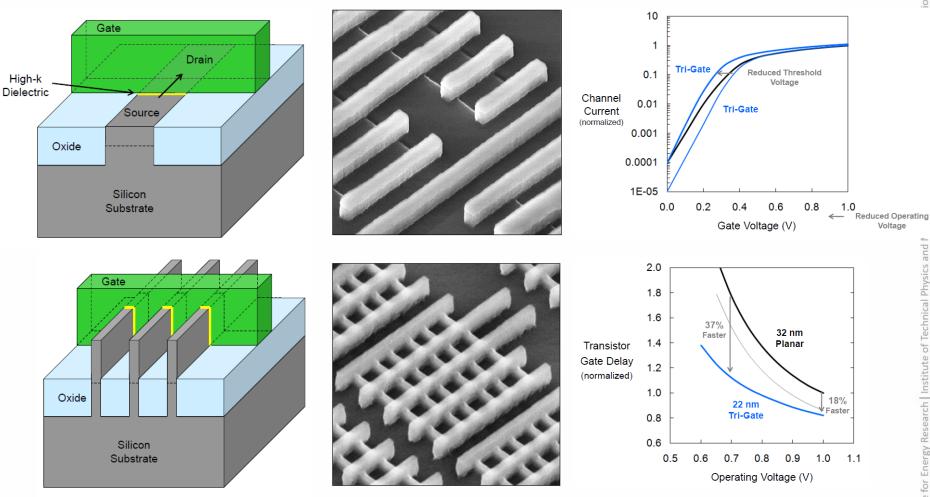
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# (intel)

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#### **PLANAR vs. 3D TRANSISTOR**



# **TECHNOLOGY: from SAND to PROCESSOR**

#### (2011 - 3D TRI-GATE MOS)

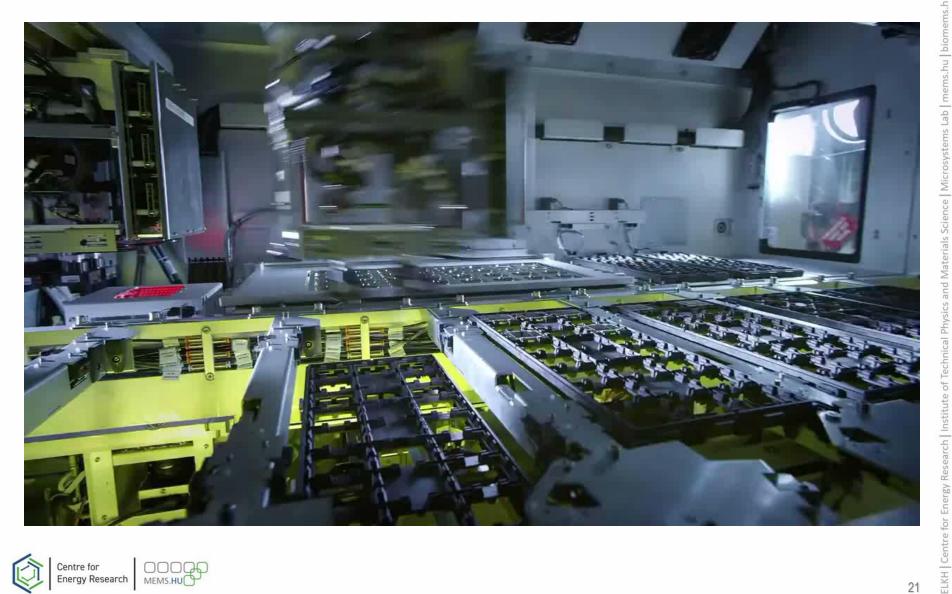
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#### **INFRASTRUCTURE – MICRO / NANO – INTEL FAB**





# TSMC 1987 - TODAY

TSMC's 5nm (N5) Fin Field-Effect Transistor (FinFET) technology successfully entered volume production in the second quarter of 2020.



Revenue for January through September 2021 totaled NT\$1,149.23 billion, an increase of 17.5 percent compared to the same period in 2020.



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# **BEYOND MOORE LAW ...**

MOBILE

By Ali Salman

Nov 3, 2021 14:29 EDT

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TSMC to Use 4nm Process For A16 Bionic Chips on iPhone 14

**f** SHARE

🕑 TWEET

🤠 SUBMIT

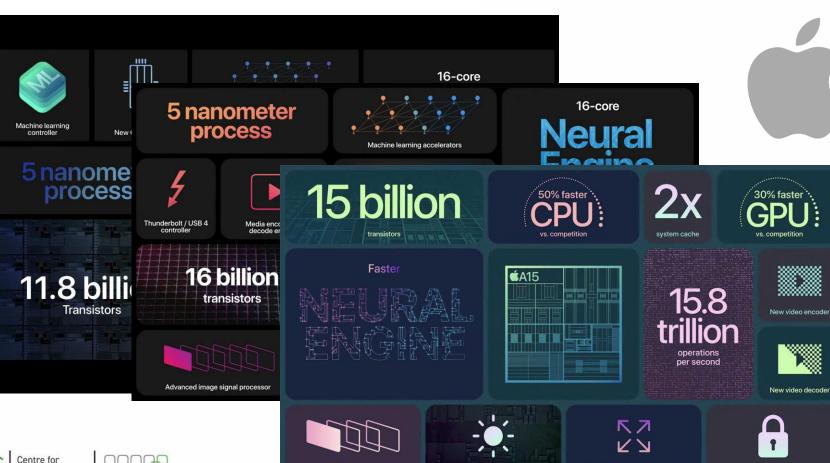






Secure Enclave

Wider lossy compression support



New display engine

New ISP

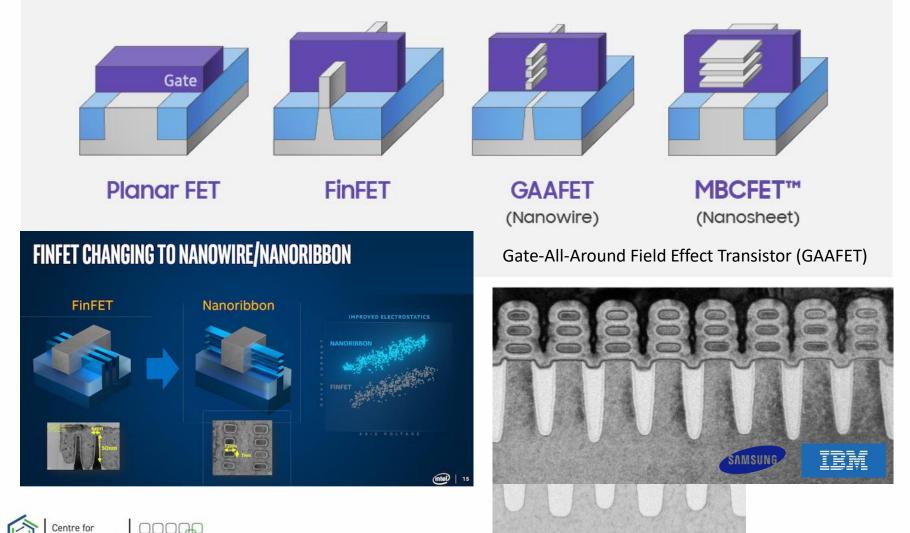
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# **TECHNOLOGY: BEYOND 3D TRI-GATE**

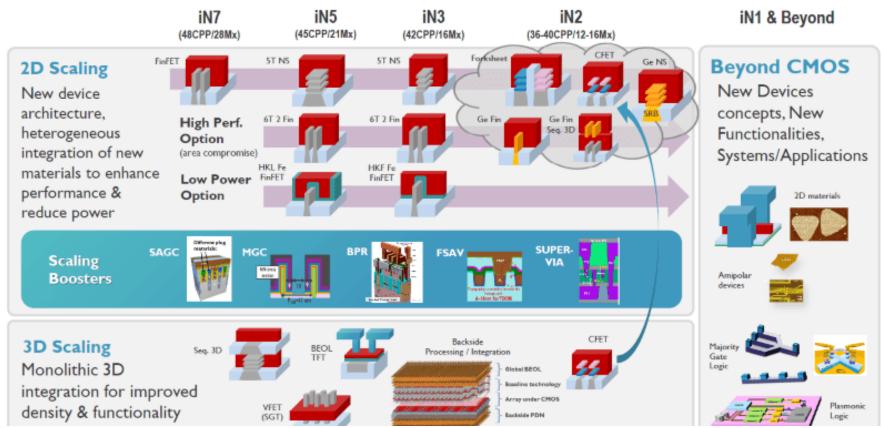


#### Multi-Bridge Channel FET (MBCFET)



# **CMOS AND BEYOND CMOS**

#### IMEC VIEW OF LOGIC ROADMAP



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#### Alternative technologies:

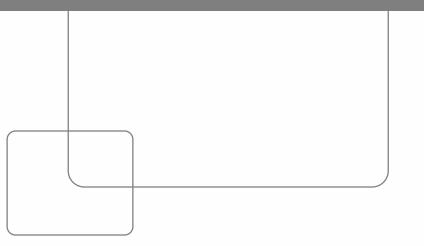
Superconducting technology **Spintronics** 

Quantum Computing **Photonics** 

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# MORE THAN MOORE REVOLUTION of MEMS





# **MEMS: SI (SOLID STATE) MICROSENSORS**

#### **MEMS:** micro-electromechanical systems

#### **Example: automotive applications**

- Engine / gear diagnostics and control
- Life- and trafic safety
- Comfort

Night vision

Front airbag sensors

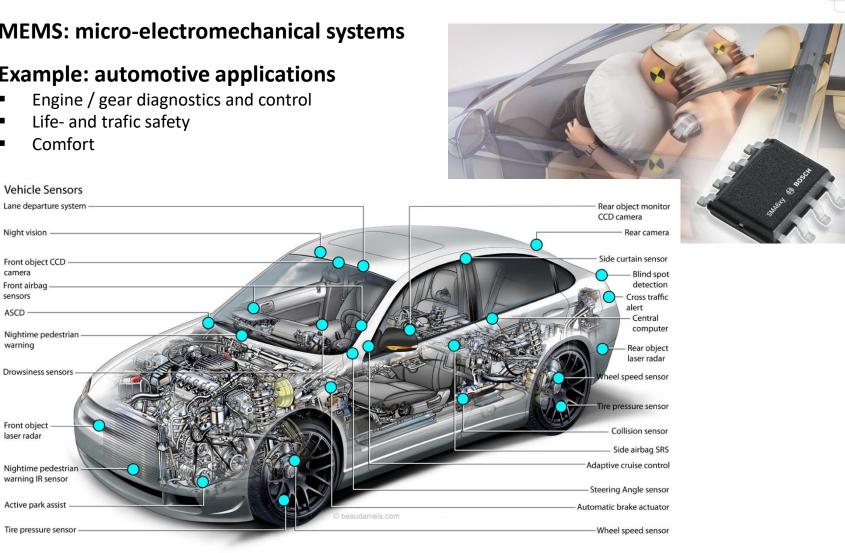
camera

ASCD

warning

Front object

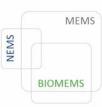
laser radar



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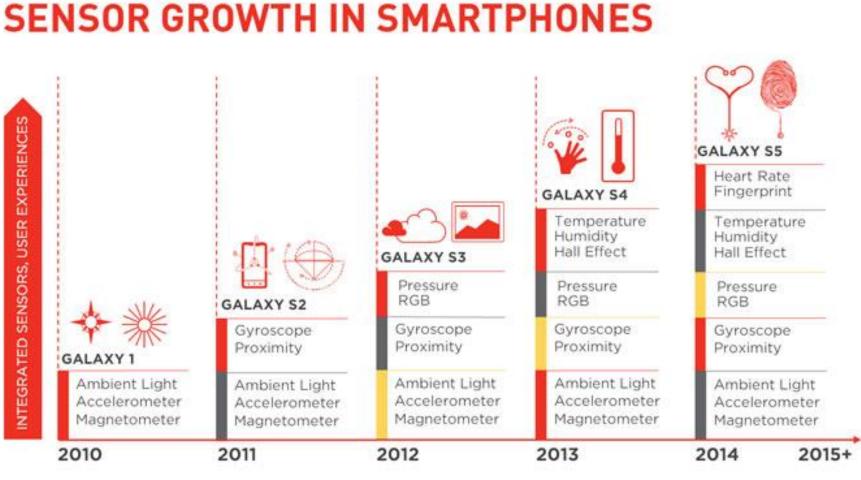
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#### **GUESS WHO?**





#### **DISASSEBLE OUR VIRTUAL SMARTPHONE**



Sources: Driven by Apple and Samsung, Light Sensors Achieve Double-Digit Revenue Growth, IHS, June 30, 2013; MEMS: Looking back at 2014 and 5 years outlook, IHS, November 2014; Light and Proximity Sensors - A Market Ready for Explosive Growth, Tony Rizzo, Mobility TechZone, July 30, 2013; iPhone 6 Teardown, iFixit, 2014; Apple 3G iPhone Teardown Report, Portelligent, 2008; MEMS Microphone Market Tops 2 Billion Units, Mobile Dev Design, March 4, 2013



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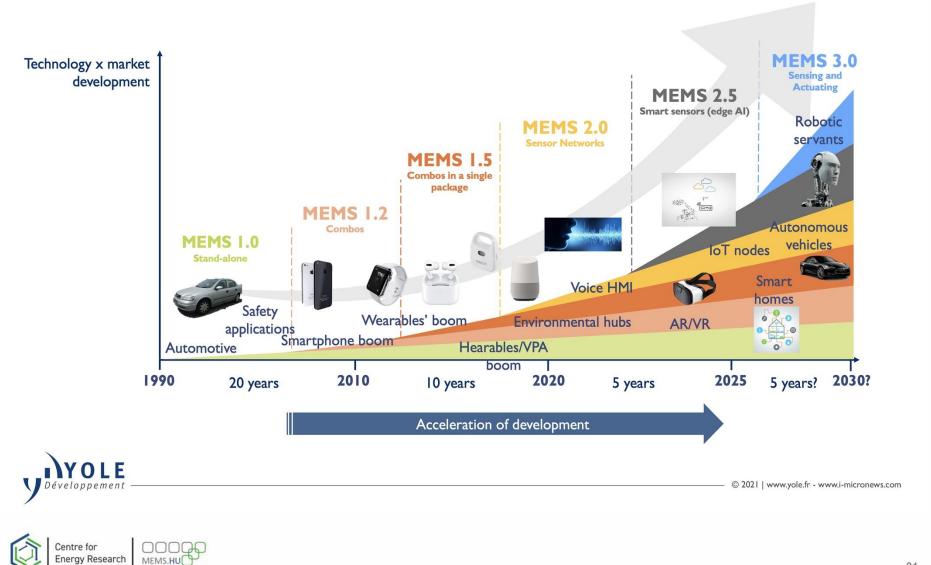
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#### NEMS **SMARTPHONE'S FUTURE** BIOMEMS Fingerprint (iPhone 5s 1st major use) Emerging tech: Hall Effect Force (Samsung Galaxy) Pulse Pressure/Barometer Gas/chemical ·UV (Samsung Galaxy) Thermal imaging Heart rate 1G 2G **5G** 3G **4**G •Etc. (Samsung 1981 1992 2001 2007 2020 Accel/ Galaxy) Magneto combo Gyroscope Temperature Accelerometer Proximity (iPhone4) Humidity (Samsung Magnetometer RGB, proximity, Ambient Light SCH-S310 (Samsung (iPhone3) gesture (Original possibly 1st Galaxy) (Samsung iPhone) Accel/ application) Galaxy) Gyro combo -High performance 9-axis motion RGB MEMS microphones combo (iPhone4) (iPhone4) 2005 2006 2007 2008 2010 2012 2014 2009 2011 2013 2015 +Apple iPhone introduced Samsung Galaxy has more than 10 with 3 sensors sensors, most of any phone on market

Sources: This little motion sensor went to the market..., Sonja Thompson, IT News Digest, March 22, 2007; Willie D. Jones, IEEE Spectrum, A Compass in Every Smartphone, January 29, 2010; Consumers boost MEMS combo sensors, Electronic Product Design and Test, March 19, 2014; Samsung Turns up the Pressure on Competition with Pressure Sensor in Galaxy S4, IHS, March 20, 2013; Behind the sixth sense of smartphones: the Snapdragon processor sensor engine, Qualcomm, April 24, 2014; MEMS for Cell Phones & Tablets, Yole Developpement, May 2012; Fairchild, Emergence of a \$Trillion MEMS Sensor Market, SensorCon, 2012; MEMS Microphone Market Tops 2 Billion Units, Mobile Dev Design, March 4, 2013

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#### "SMART" EVOLUTION



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#### STATE OF THE ART

